

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No	08/846,671
Filing Date	April 30, 1997
Inventorship	
Assignee	
Group Art Unit	
Examiner	
Attorney's Docket No	
Customer No.	
Title: Undoped Silicon Dioxide as Etch Stop	for Selective Etch of Doped Silicon
Dioxide	•

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. Copies of the cited art are attached hereto. No admission is made regarding whether all the submitted references are prior art.

This Supplemental Information Disclosure Statement is being filed before the mailing of a first office action after the filing of a request for continued examination. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: 3-22-04

Mark S. Matkin Reg. No. 32,268

O I P S			J.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2041			SERIAL NO. 08/846,671		
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THE WAY	ARK CO				FILING DATE April 30, 1997		GRC 1763			
U.S. PATEN		UMENTS			-					
*Examiner's Initials		Document Number	Date	Name		Class	Subclass	Filing If Appro	Date priate	
	AA	4,672,740	06/16/87	Shirai et al.						
	AB	5,229,311	07/20/93	Lai et al.						
	AC	5,393,704	02/28/95	Huang et al.						
	AD	5,705,427	01/06/98	Chan et al.	·					
	AE									
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FOREIGN F	ATENT	DOCUMENTS		T		; •		: •		
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OTHER RE	FEREN	CES (including Author,	Title, Date, Pe	ertinent Pages, Etc.)				<u> </u>		
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